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PATENTS, TRADEMARKS, COPYRIGHTS

AND RELATED MATTERS

OF COUNSEL
IRVING POWERS
DONALD G. LEAVITT
RICHARD G. HEYWOOD

STUART N. SENNIGER (1921-1997)

Application of Gregory Michael Wilson et al.

Serial No. 09/608,302

Filed June 30, 2000

For

METHOD AND APPARATUS FOR FORMING A SILICON

WAFER WITH A DENUDED ZONE

Attorney Docket No. MEMC 98-4650(2293)

Office of Initial Patent Examination Customer Service Center Assistant Commissioner for Patents Washington, D.C. 20231

Sir:

We have received the corrected filing receipt in the above-referenced U.S. patent application.

The filing receipt still shows the inventors as Gregory Micheal Wilson, Chesterfield, MO; Micheal John Ries, St. Charles, MO. whereas the correct information Gregory Michael Wilson, Chesterfield, MO; Michael John Ries, St. Charles, MO.

Please send us a corrected filing receipt.

Respectfully submitted,

Edward J. Hejlek, Reg. No. 31,525

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Group Art Unit 1765

J6W 12 200

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UNITED STATES PATENT AND TRADEMARK OFFICE
WASHINGTON, D.C. 2023
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Bib Data Sheet

SERIAL NUMBE 09/608,302	FILING DATE 06/30/2000 RULE _	CLASS 438		P ART UNIT 1765	ATTORNEY DOCKET NO. MEMC-98-4650 (2293)				
Michael John ** CONTINUING D ** FOREIGN APPL	hael Wilson, Chesterfield n Ries, St Charles, MO; PATA ***********************************	***			·	RECEIVED TECHNOLOGY CENTER			
Foreign Priority claimed 35 USC 119 (a-d) condition met Verified and ACTORESS 000321	state or country MO	SHEE DRAW 4		MS	INDEPENDENT CLAIMS 2				
TITLE Method and appar	atus for forming a silicon	wafer with a denuded	zone						
FILING FEE FEES: Authority has been given in Paper No to charge/credit DEPOSIT ACCOUNTS for following:				All Fees 1.16 Fees (Filing) 1.17 Fees (Processing Ext. of time) 1.18 Fees (Issue) Other Credit					



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APPLICATION NUMBER	FILING DATE	GRP ART UNIT	FIL FEE REC'D	ATTY.DOCKET.NO	DRAWINGS	TOT CLAIMS	IND CLAIMS	
09/608,302	06/30/2000	1765	840	MEMC-98-	4	20	2	

000321
SENNIGER POWERS LEAVITT AND ROEDEL
ONE METROPOLITAN SQUARE
16TH FLOOR
ST LOUIS, MO 63102

FILING RECEIPT

OC00000005569646

Date Mailed: 11/21/2000

Receipt is acknowledged of this nonprovisional Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Customer Service Center. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the PTO processes the reply to the Notice, the PTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

Gregory Michael Wilson, Chesterfield, MO; / Michael Michael John Ries, St Charles, MO; / Michael

Continuing Data as Claimed by Applicant

Foreign Applications

If Required, Foreign Filing License Granted 08/30/2000

Title

Method and apparatus for forming a silicon wafer with a denuded zone

Preliminary Class

438

Data entry by : DADE, JOAN

Team: OIPE

Date: 11/21/2000

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